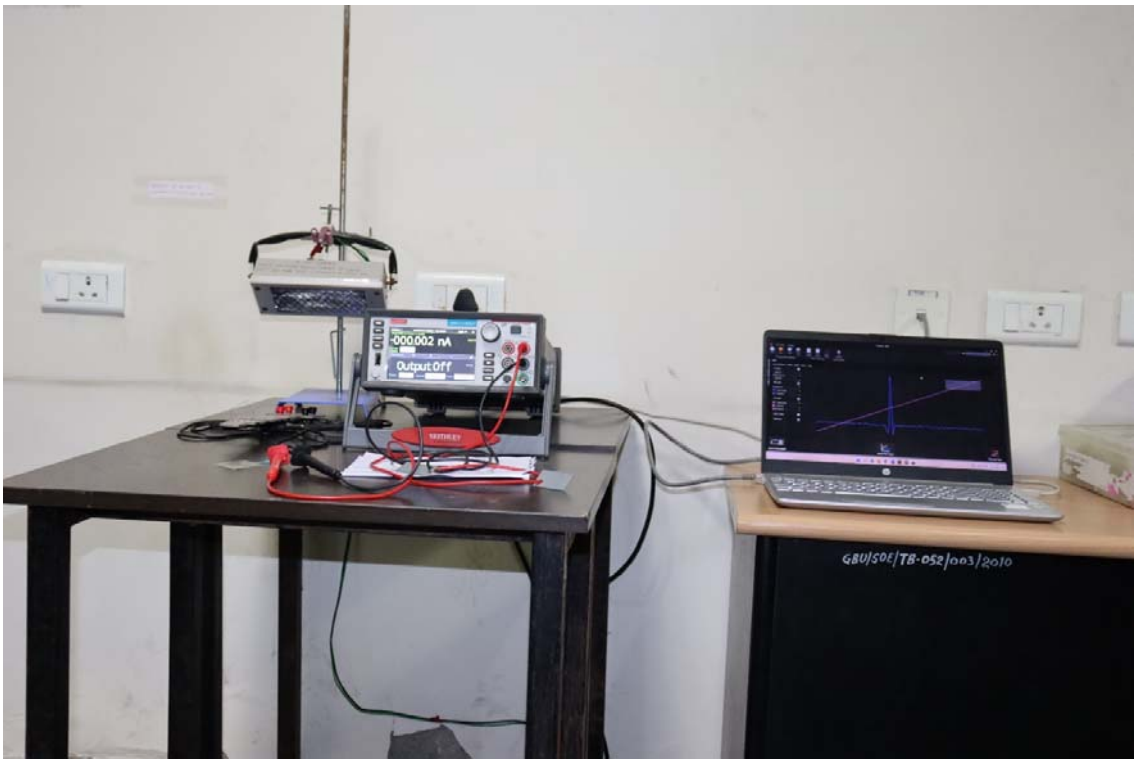


Device characteristics Measurement System (Keithley 2450 source meter)

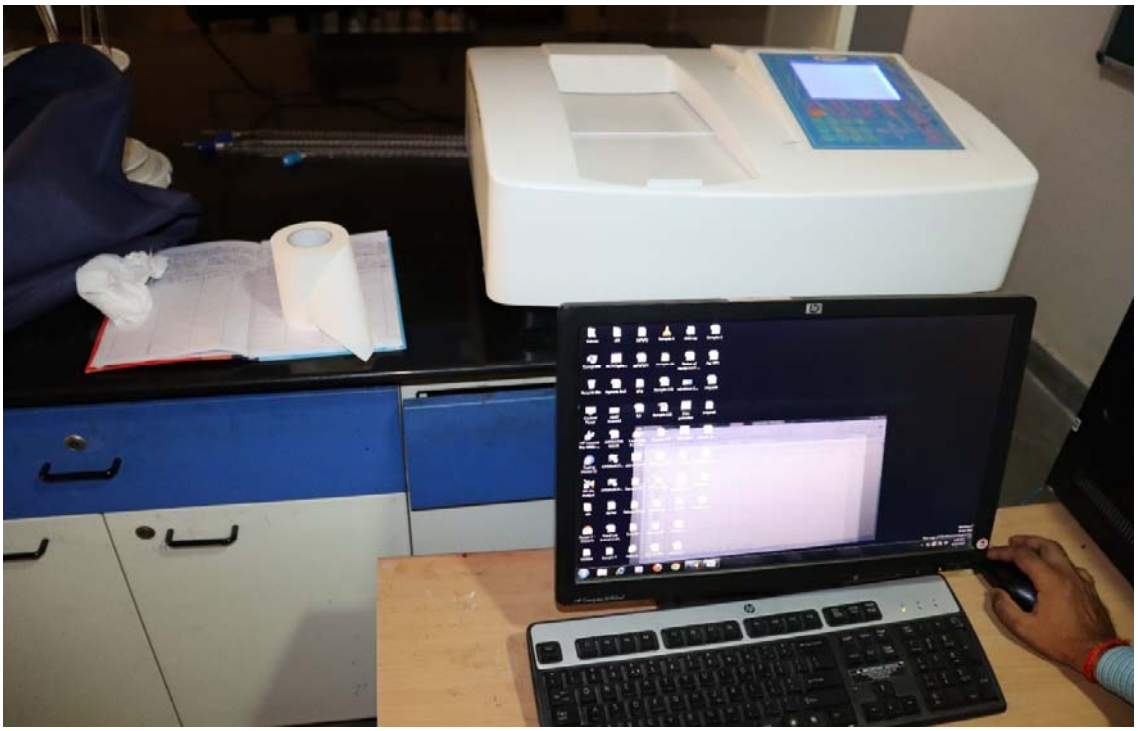
Thin film deposition (Thermal evaporation)

Nanostructured thin film growth by chemical vapor deposition (CVD)

Thin film deposition by spin coating

Furnace and oven for thermal treatment of materials and micro samples synthesis by solid state diffusion

Autoclave



UV-Vis spectrophotometer

Optical bench for research in photonics

Hall effect measurement system at research level for quantifying charge carriers' concentration

Four probe measurement system for charactering the semiconductors

Microwave attenuation measurements

Manually controlled spectrometer for rough testing of materials

Precision Interferometer

Photonics and Nanophotonic Lab

Research Labs corridor

Optical bench from diffraction measurements

Instrument for Photo Catalysis measurements

Autoclave for hydrothermal growth of thin film

Experimental Lab (Research)